

Hierarchical Current Density Verification for Electromigration Analysis in Arbitrarily Shaped Metallization Patterns of Analog Circuits

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Overview

- Motivation and previous works
- Design flow
- How do we characterize pin currents?
- How is current density calculated?
- How do we visualize and verify current density?
- Experimental results
- Summary

Motivation

Analog circuits for automotive applications

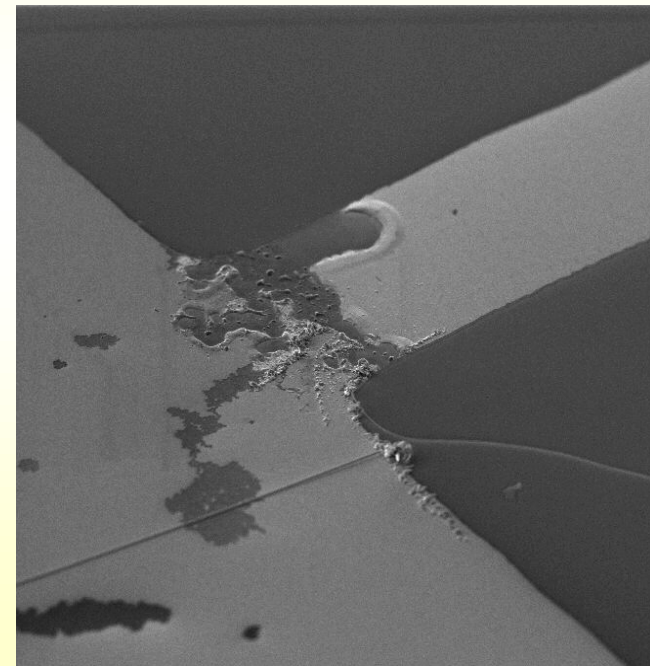
- High interconnect currents
- Ongoing reduction of circuit feature sizes, including interconnects



- **Insufficiently dimensioned cross section area** of interconnects



- High current densities which might lead to **electromigration**



<http://ap.polyu.edu.hk/apavcdo/public/gallery.htm>

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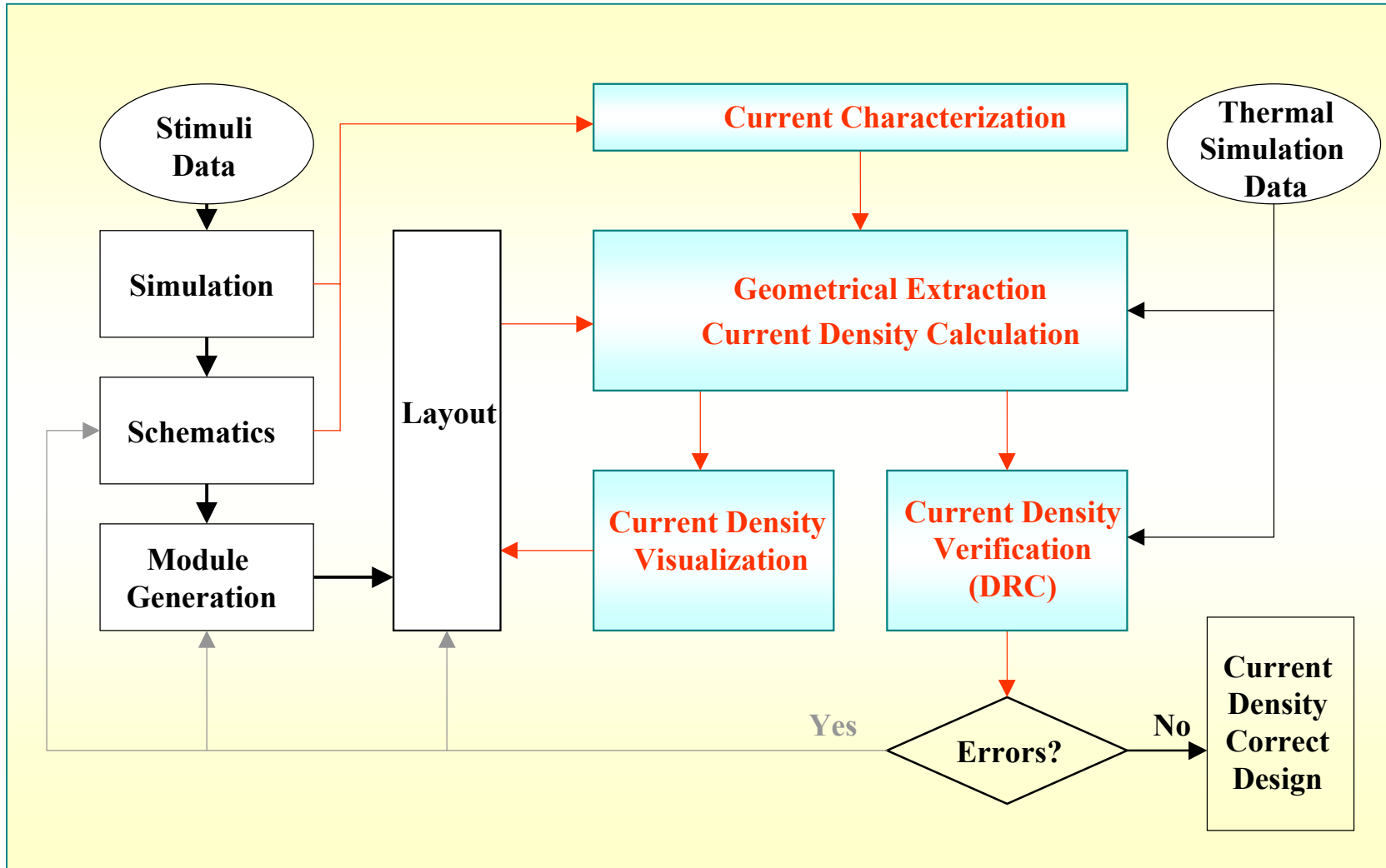
Motivation (cont.'d)

- No commercial tools available for electromigration analysis of arbitrarily shaped metallization patterns (as commonly used in analog circuits)
 - Manual current density verification is very time consuming and error prone
- ⇒ Need for an **automatic** verification methodology tailored for electromigration analysis of **arbitrarily shaped** metallization patterns **in analog circuits**

Previous Works

- **Studies of electromigration** and its relation to the mean time to failure (MTTF) of electronic circuits
[Black 1969][D'Heurle 1971][Maiz 1991][Young et al. 1994]
- Electromigration analysis in **digital systems**
[Hajj et al. 1991][Steele et al. 1998]
- Electromigration analysis in **analog circuits limited to rectangular shapes** [Adler et al. 2000]

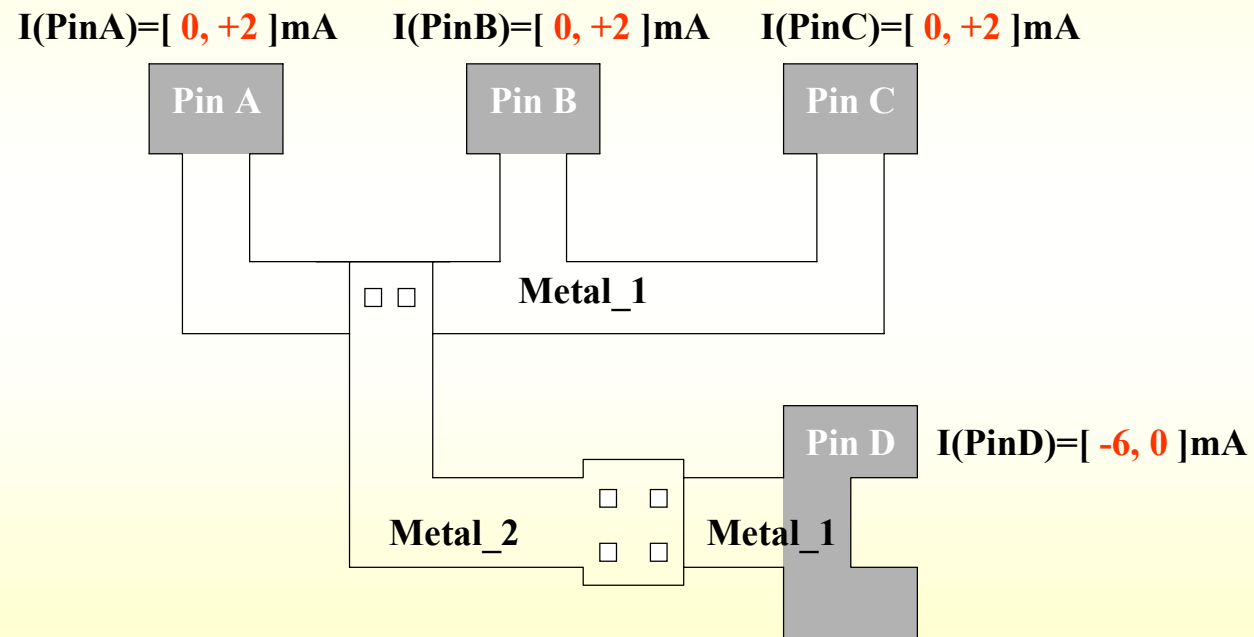
Design Flow



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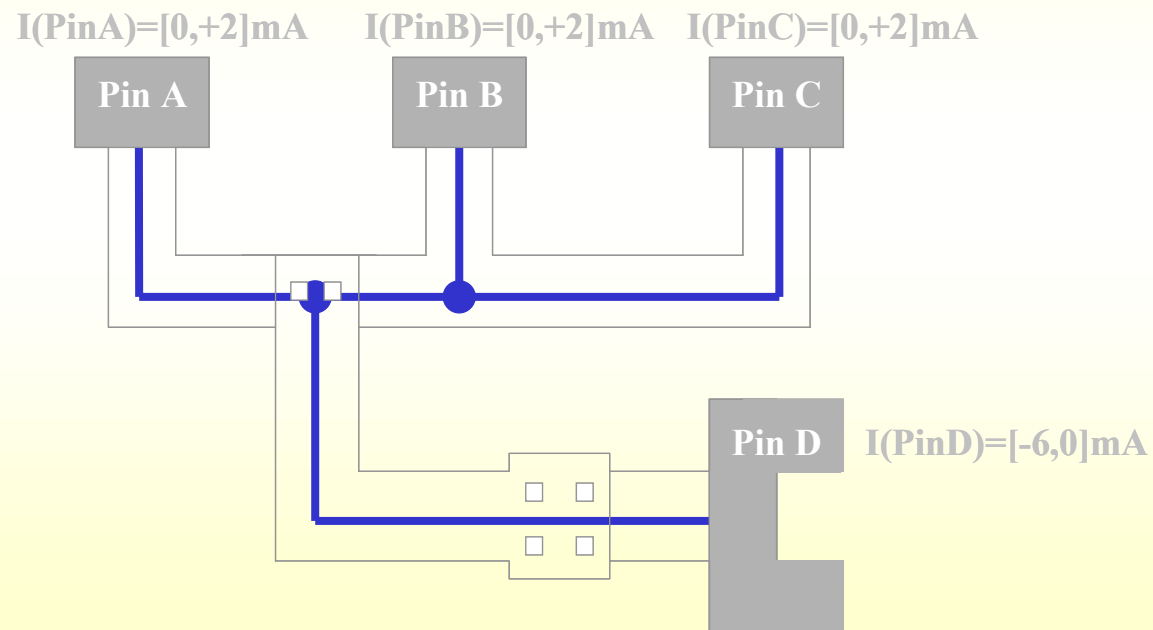
Pin Current Characterization

- Pin current values are attached as $[I_{\min}, I_{\max}]$



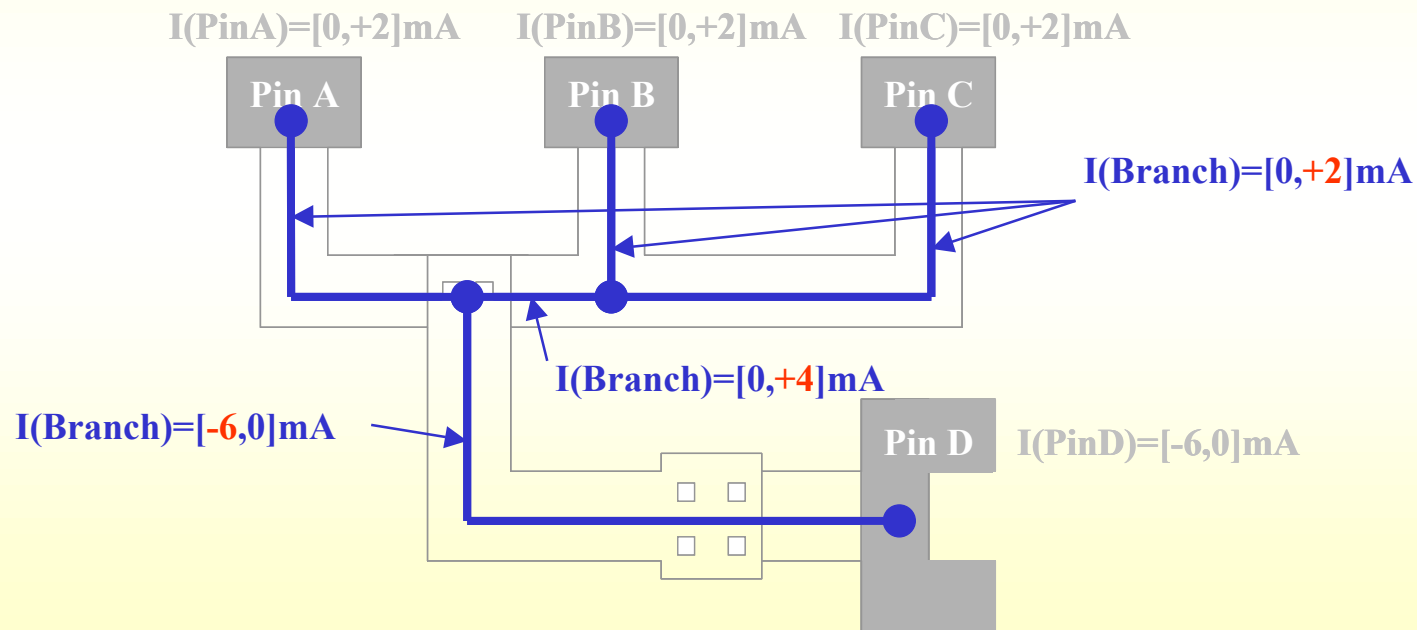
Layout Segmentation

(1) Determination of the **current graph**



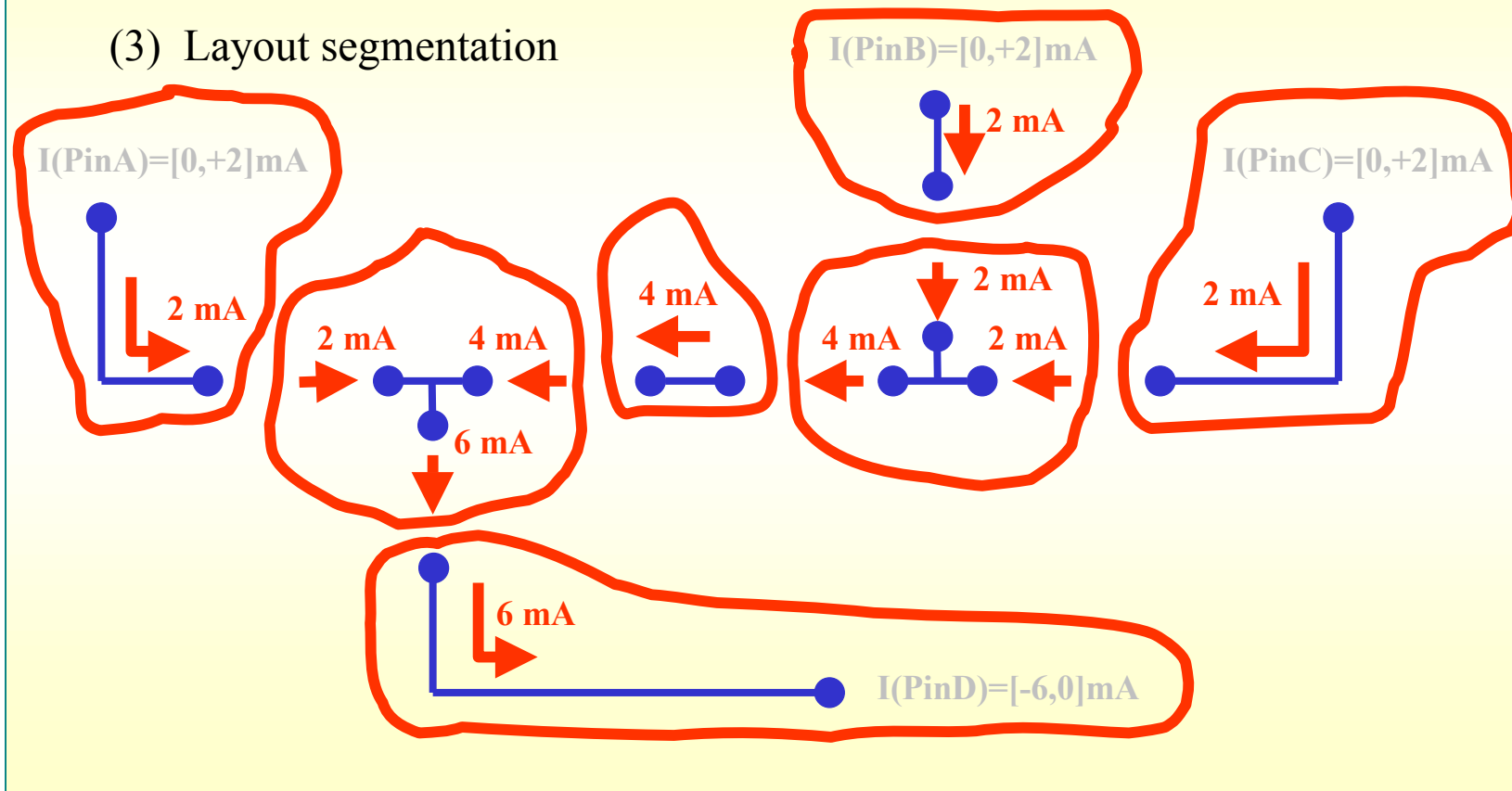
Layout Segmentation

- (1) Determination of the current graph
- (2) Worst case analysis within the **current graph**



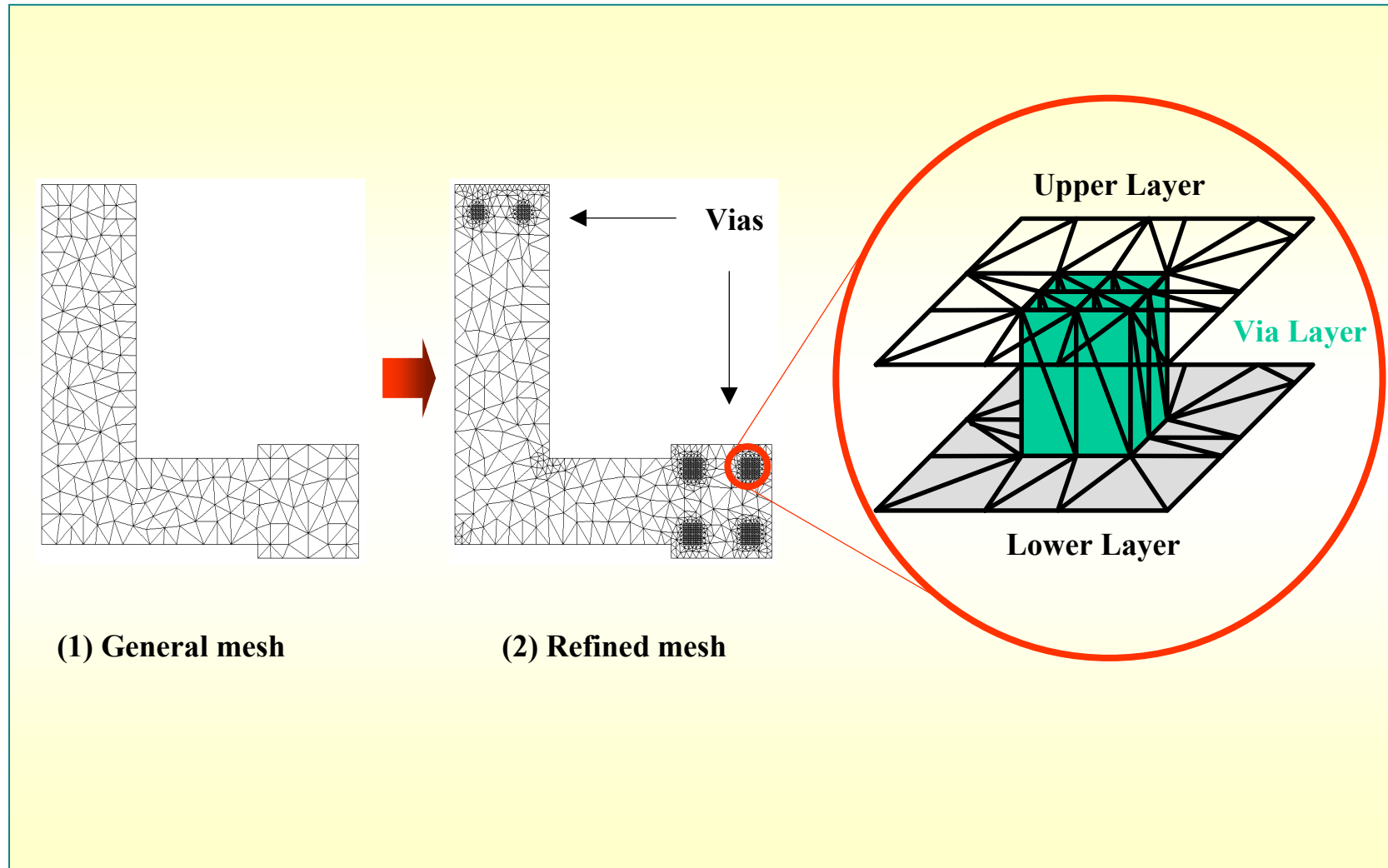
Layout Segmentation

- (1) Determination of the current graph
- (2) Worst case analysis within the current graph
- (3) Layout segmentation



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Geometry Extraction for Finite Element Method



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Current Density Calculation

- **Given:**
Segments from layout segmentation with geometry and currents
- **Goal:**
For each layout segment determine current density by using **Maxwell's equation**
- **Solution:**
In order to obtain the potential field configuration $\varphi(x,y,z)$, the **Laplacian equation** has to be solved using the Finite Element Method (FEM)
(→ see Section 4.2 in paper)

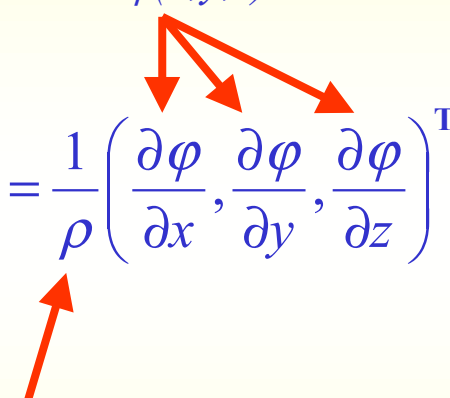
$$\underline{J} = \frac{1}{\rho} \left(\frac{\partial \varphi}{\partial x}, \frac{\partial \varphi}{\partial y}, \frac{\partial \varphi}{\partial z} \right)^T$$

$$\Delta \varphi = \frac{\partial^2 \varphi}{\partial x^2} + \frac{\partial^2 \varphi}{\partial y^2} + \frac{\partial^2 \varphi}{\partial z^2} = 0$$

Current Density Calculation: Incorporating Thermal Simulation Data

- Problem:
Calculating current density is temperature dependent because any change in the temperature distribution influences the gradient of the electrical potential field $\varphi(x,y,z)$

Maxwell's equation
$$\underline{J} = \frac{1}{\rho} \left(\frac{\partial \varphi}{\partial x}, \frac{\partial \varphi}{\partial y}, \frac{\partial \varphi}{\partial z} \right)^T$$

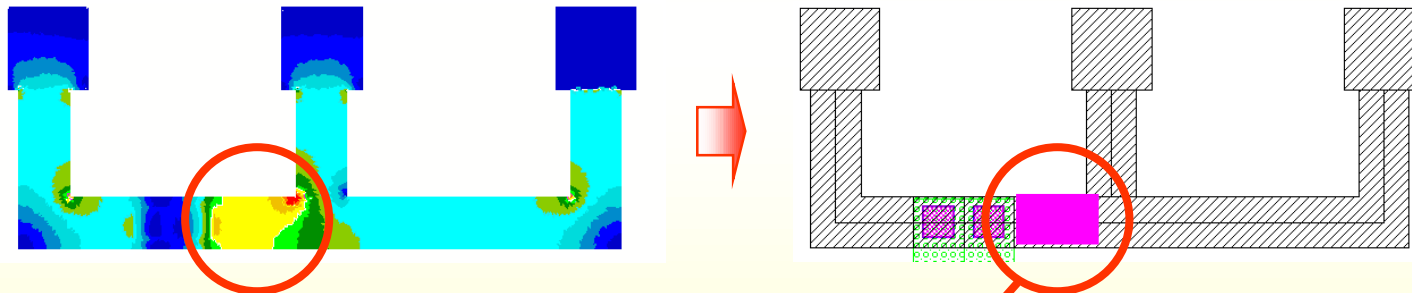


- Solution:
Electrical conductivity $\rho(x,y,z)$ is determined under consideration of a thermal potential field

Current Density Verification

- Does calculated current density value **exceed the reference value of the maximum current density** of the layer material?

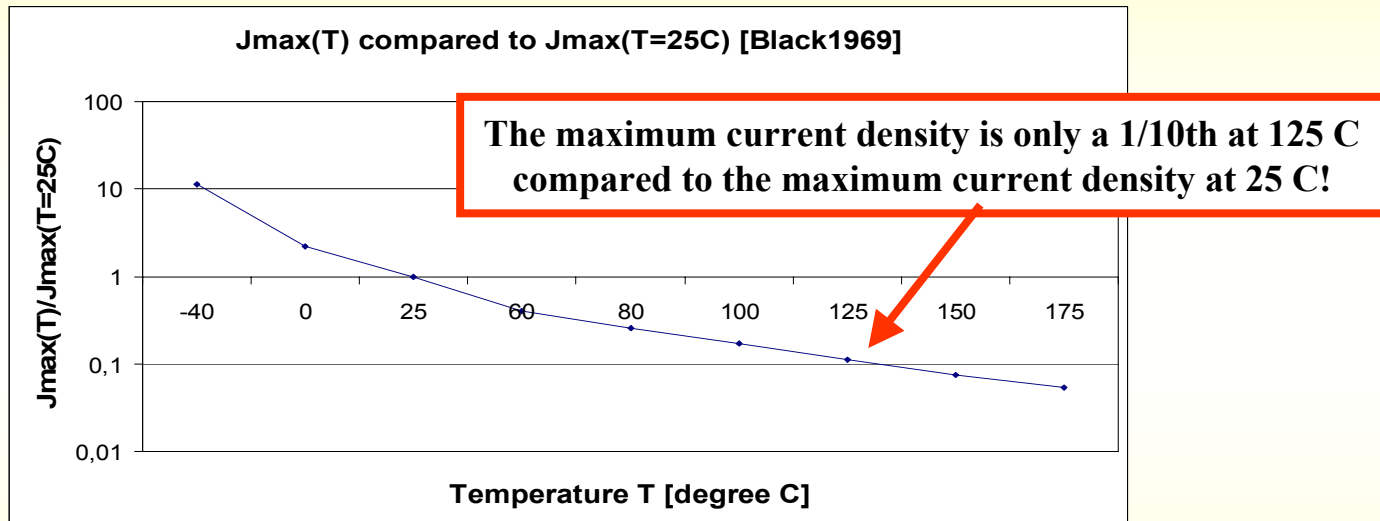
⇒ “Current density DRC”



Calculated current density > Permissible maximum current density

Current Density Verification: Incorporating Thermal Simulation Data

- Problem:
Verifying current density is temperature dependent because acceptable maximum current varies with temperature



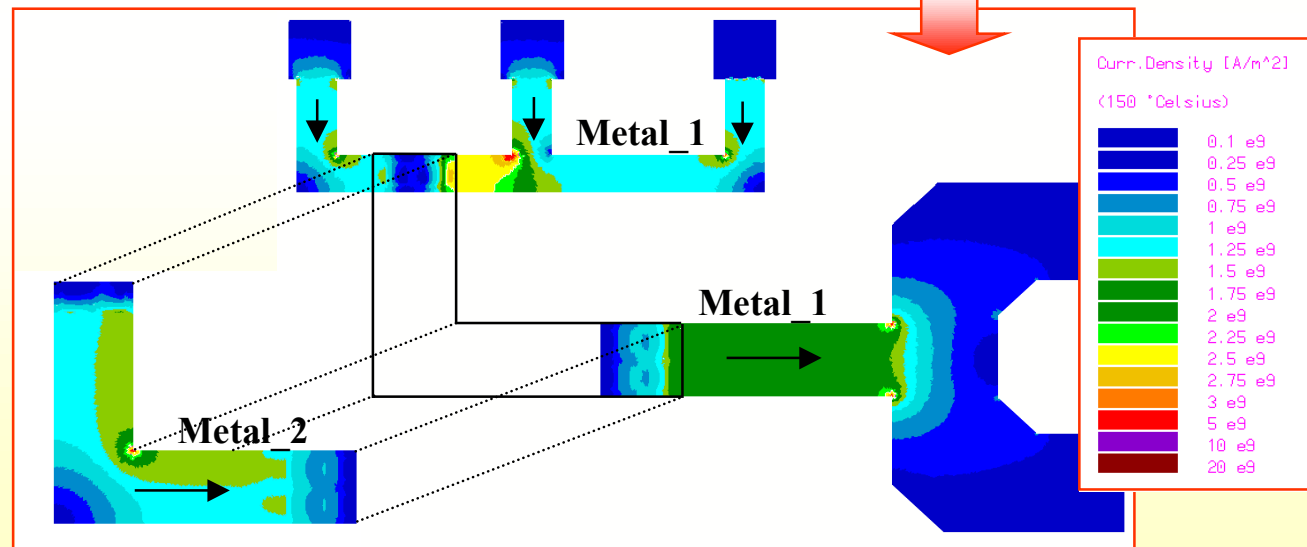
- Solution:
In order to verify if calculated current density is acceptable, we compare calculated current density with a reference current density **scaled by the actual working temperature**

Current Density Visualization

- Time-dependant pin current values
- No layout segmentation

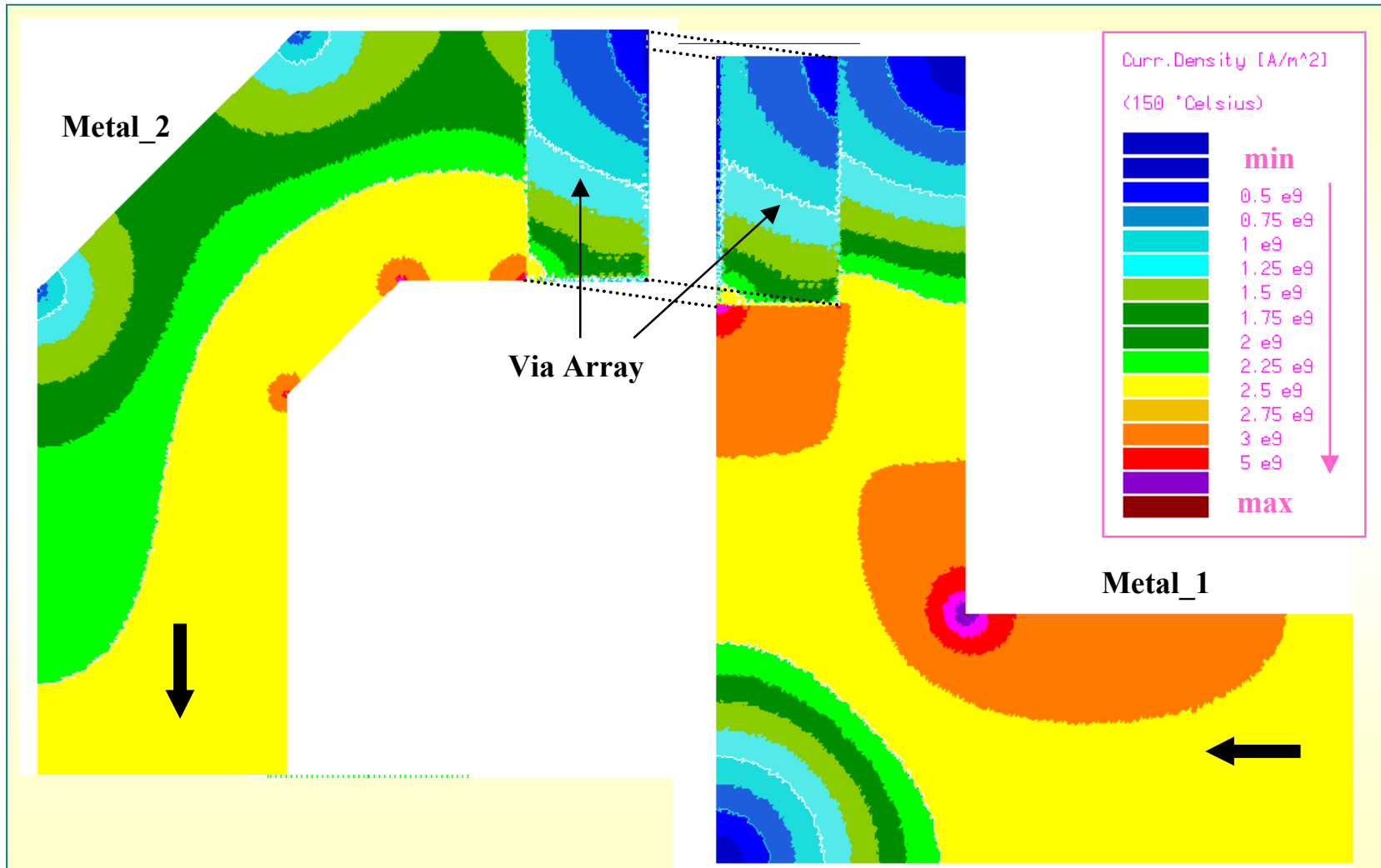
**Geometrical Extraction
Current Density Calculation**

**Current Density
Visualization**



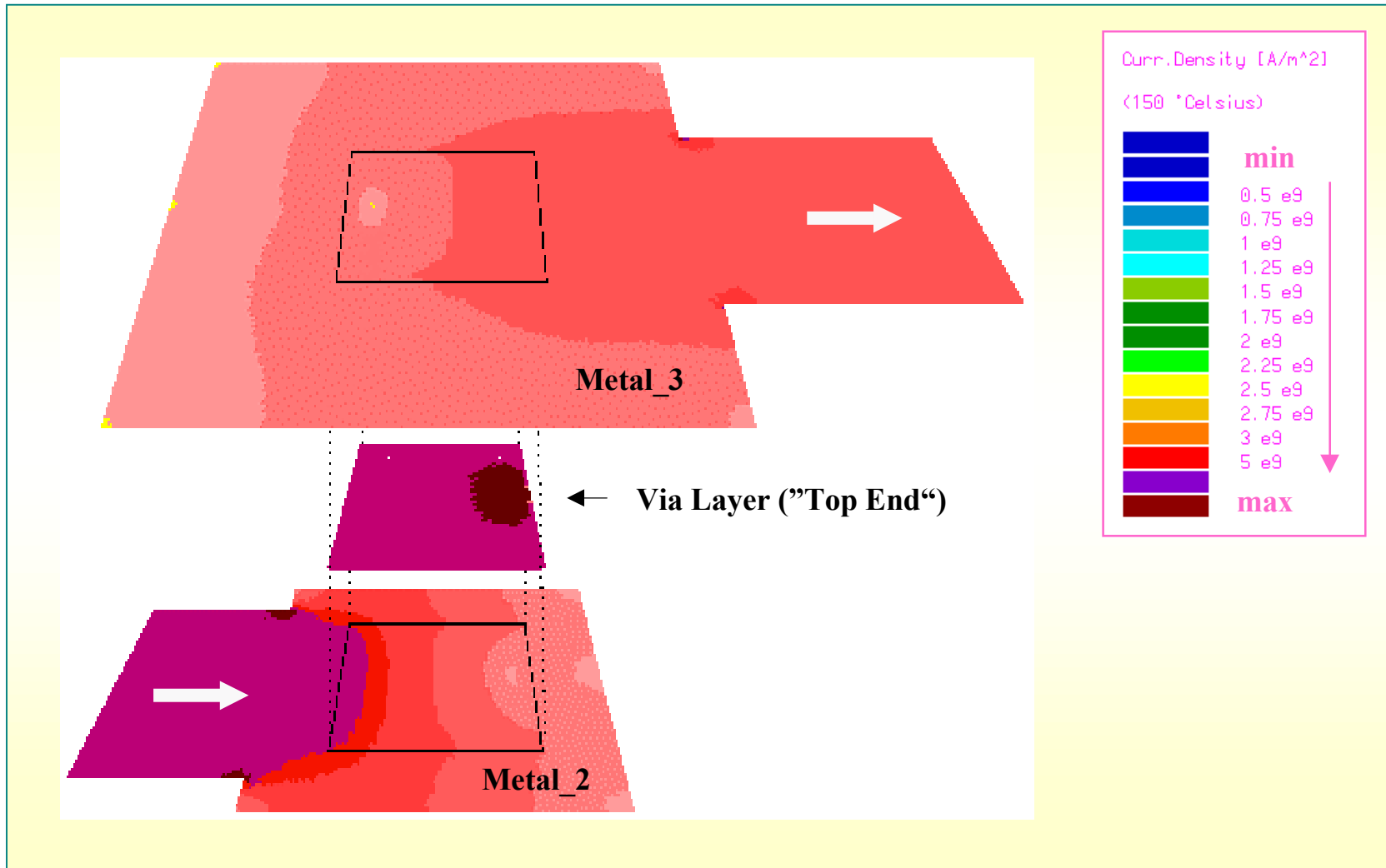
Jerke, G., Lienig, J: Hierarchical Current Density Verification for Electromigration Analysis in Arbitrarily Shaped Metallization Patterns of Analog Circuits, *Proceedings Design, Automation and Test in Europe (DATE)*, March 2002, pp. 464-469

Results: Interconnect and Via Array



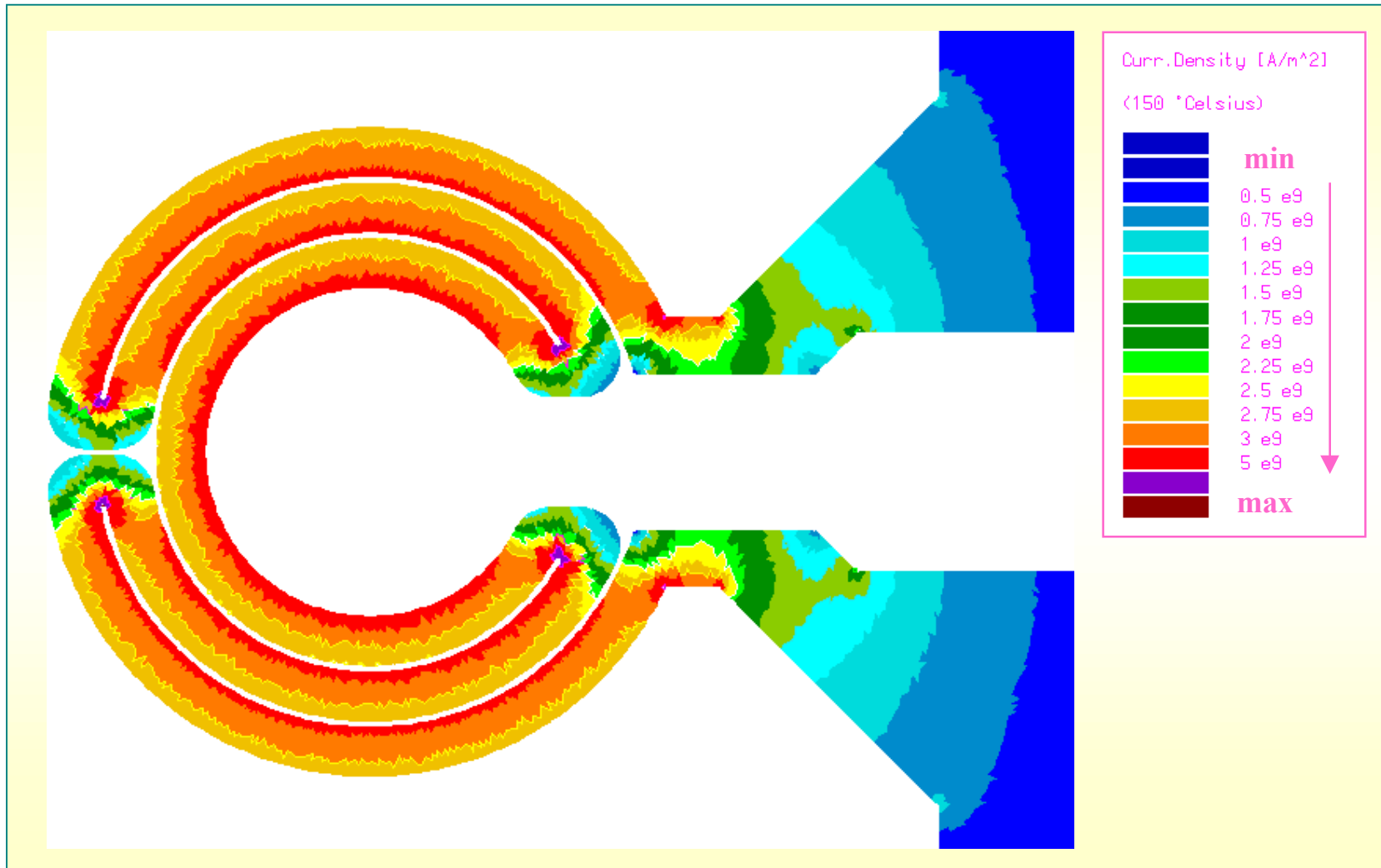
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Results: Single Via



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Results: MEMS Structure



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Summary

- New methodology for **hierarchical verification of current densities** in **arbitrarily shaped** analog circuit layouts
- **Quasi-3D model for verifying irregularities** like vias and via edge stress, using “bee-comb”-like structures
- **Incorporating thermal simulation data** to account for temperature dependency of electrical field configuration and electromigration
- Option of integrating our methodology as an **automated current density DRC** in virtually any IC-design flow
- **Verification** of our methodology on “real world” analog circuits

Appendix: Current Density Calculation (FEM)

(1) Perform triangulation

(2) Use linear assumption for triangles Δ

$$\varphi = a_0 + a_1x + a_2y$$

(3) Generate the *Element Equations*

$$\underline{i}_{\Delta} = \underline{Y}_{\Delta} \cdot \underline{\varphi}_{\Delta}$$

(4) Assemble the *System Matrix* with all triangles

$$\underline{i} = \underline{Y} \cdot \underline{\varphi}$$

(5) Apply boundary constraints

$$\underline{i}_{BC} = \underline{Y} \cdot \underline{E}^{BC} \cdot \underline{\varphi}$$

(6) Solve equation system (e.g., with Conjugated Gradient Method)